

## Origin of enhanced thermal atomic layer etching of amorphous HfO<sub>2</sub>

**URL:** <https://avs.scitation.org/doi/10.1116/6.0001614>

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**Research Lines:** [Ab-Initio Electronic Structure Methods](#)

**Publication:** Journal of Vacuum Science & Technology

**Place Published:** AVS

**Volume / Pagination:** 40 / 022604

**Palabras clave:** [amorphous](#), [Atomic Layer Etching](#), [HfO<sub>2</sub>](#), [surfaces](#)

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**Source URL (retrieved on 27 Sep 2024 - 06:57):** <https://www.bsc.es/es/research-and-development/publications/origin-enhanced-thermal-atomic-layer-etching-amorphous-hfo2>